

1731

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Akira IKUSHIMA, Kazuya SAITO, Takashi MIURA
and Shogo NASUDA
Serial no. : 09/848,246
Filed : May 3, 2001
For : METHOD OF MANUFACTURING AN OPTICAL
FIBER
Group Art Unit : 1731
Examiner : John M. Hoffmann
Docket : ADACHI P163USP2

The Commissioner for Patents
U.S. Patent & Trademark Office
P. O. Box 1450
Alexandria, VA 22313-1450

ADDENDUM TO INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Further to the Information Disclosure Statement mailed under a May 3, 2001 Express Mailing date, enclosed is a copy of the three (3) references which was not previously available and indicated as "(to follow)".

This submission is believed to complete the filing of the above referenced Information Disclosure Statement. If any further action on the part of the Applicant is necessary to make this art properly of record, the Examiner is respectfully requested to contact the undersigned.

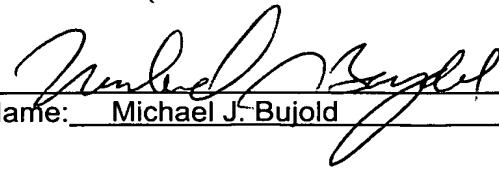
In the event that there are any fee deficiencies or additional fees are payable, please charge the same or credit any overpayment to our Deposit Account (Account No. 04-0213).

Respectfully submitted,


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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service, with sufficient postage, as First Class Mail in an envelope addressed to: Director of the United States Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. December 5, 2003.

By: 
Print Name: Michael J. Bujold



PATENT AND TRADEMARK OFFICE
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(Use several sheets if necessary)

Atty Docket: A710CHI P163USP2

Examiner: John Hoffmann

Group: 1731

Applicant: Akira IKUSHIMA, Kazuya SAITO, Takashi
MIURA and Shogo NASUDA

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Sub- Class	Filing Date, if Appropriate
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